

Roger T Howe

List of Publications by Year in descending order

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28
papers

3,071
citations

361413
20
h-index

526287
27
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28
all docs

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docs citations

28
times ranked

1934
citing authors

#	ARTICLE	IF	CITATIONS
1	Micron-gap spacers with ultrahigh thermal resistance and mechanical robustness for direct energy conversion. <i>Microsystems and Nanoengineering</i> , 2019, 5, 31.	7.0	22
2	Surface Photovoltage-Induced Ultralow Work Function Material for Thermionic Energy Converters. <i>ACS Energy Letters</i> , 2019, 4, 2436-2443.	17.4	23
3	Back-gated graphene anode for more efficient thermionic energy converters. <i>Nano Energy</i> , 2017, 32, 67-72.	16.0	57
4	Engineering Ultra-Low Work Function of Graphene. <i>Nano Letters</i> , 2015, 15, 6475-6480.	9.1	75
5	Microfabricated Thermally Isolated Low Work-Function Emitter. <i>Journal of Microelectromechanical Systems</i> , 2014, 23, 1182-1187.	2.5	83
6	DFT Study of Atomically-Modified Alkali-Earth Metal Oxide Films on Tungsten. <i>Journal of Physical Chemistry C</i> , 2014, 118, 11303-11309.	3.1	13
7	Microbead-separated thermionic energy converter with enhanced emission current. <i>Physical Chemistry Chemical Physics</i> , 2013, 15, 14442.	2.8	35
8	Thermionic current densities from first principles. <i>Journal of Chemical Physics</i> , 2013, 138, 204701.	3.0	10
9	An orbital-overlap model for minimal work functions of cesiated metal surfaces. <i>Journal of Physics Condensed Matter</i> , 2012, 24, 445007.	1.8	29
10	Smart-cut layer transfer of single-crystal SiC using spin-on-glass. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2012, 30, 042001.	1.2	10
11	Optimal emitter-collector gap for thermionic energy converters. <i>Applied Physics Letters</i> , 2012, 100, .	3.3	118
12	A model for emission yield from planar photocathodes based on photon-enhanced thermionic emission or negative-electron-affinity photoemission. <i>Journal of Applied Physics</i> , 2012, 112, .	2.5	53
13	Vacuum microsystems for energy conversion and other applications. , 2011, , .		2
14	Electromechanical Sensing of Charge Retention on Floating Electrodes. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 150-156.	2.5	11
15	Photon-enhanced thermionic emission for solar concentrator systems. <i>Nature Materials</i> , 2010, 9, 762-767.	27.5	442
16	Effect of excimer laser annealing on the structural properties of silicon germanium films. <i>Journal of Materials Research</i> , 2004, 19, 3503-3511.	2.6	10
17	Polysilicon integrated microsystems: technologies and applications. <i>Sensors and Actuators A: Physical</i> , 1996, 56, 167-177.	4.1	81
18	Slide film damping in laterally driven microstructures. <i>Sensors and Actuators A: Physical</i> , 1994, 40, 31-39.	4.1	69

#	ARTICLE	IF	CITATIONS
19	A review of the chemical reaction mechanism and kinetics for hydrofluoric acid etching of silicon dioxide for surface micromachining applications. <i>Thin Solid Films</i> , 1993, 232, 1-12.	1.8	127
20	Determination of the Etching Kinetics for the Hydrofluoric Acid/Silicon Dioxide System. <i>Journal of the Electrochemical Society</i> , 1993, 140, 2339-2346.	2.9	50
21	LPCVD Silicon Dioxide Sacrificial Layer Etching for Surface Micromachining. <i>Materials Research Society Symposia Proceedings</i> , 1992, 276, 303.	0.1	6
22	Electrostatic-comb drive of lateral polysilicon resonators. <i>Sensors and Actuators A: Physical</i> , 1990, 21, 328-331.	4.1	376
23	Process Integration for active polysilicon resonant microstructures. <i>Sensors and Actuators</i> , 1989, 20, 143-151.	1.7	53
24	Laterally Driven Polysilicon Resonant Microstructures. <i>Sensors and Actuators</i> , 1989, 20, 25-32.	1.7	725
25	Surface micromachining for microsensors and microactuators. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1988, 6, 1809.	1.6	226
26	Microfabricated structures for theinsitumeasurement of residual stress, Young's modulus, and ultimate strain of thin films. <i>Applied Physics Letters</i> , 1987, 51, 241-243.	3.3	261
27	Novel microstructures for theinsitumeasurement of mechanical properties of thin films. <i>Journal of Applied Physics</i> , 1987, 62, 3579-3584.	2.5	94
28	Applications of Polysilicon Films in Microsensors and Microactuators. <i>Materials Research Society Symposia Proceedings</i> , 1987, 106, 213.	0.1	10